ABSTRACT

POLISHING TABLE REPLACEMENT APPARATUS, POLISHING TABLE REPLACEMENT METHOD, AND APPARATUS FOR REPLACING A COMPONENT OF SEMICONDUCTOR-DEVICE MANUFACTURING MACHINE

An apparatus for replacing a polishing table, which is used in a polishing apparatus for polishing a substrate such as wafer, is disclosed. The polishing table replacement apparatus (10) is used for removing a polishing table (3) from a polishing apparatus (1). This polishing table replacement apparatus (10) includes a crane (10) configured to move the polishing table (3) vertically and horizontally, a table stage (14) on which the polishing table (3) can be placed, and a table-stage tilting mechanism (15) configured to tilt the table stage (14).

Figure 8